PATENT

Attorney Docket No.: 006915 P08

RW Ref. No.: APM/001-02-CP1-8



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kenneth COLLINS, et al.

Serial No.: 10/646,526

Examiner:

Maureen G. Arancibia

Filed:

August 22, 2003

Group Art Unit:

1763

For:

PLASMA IMMERSION ION IMPLANTATION SYSTEM INCLUDING A CAPACITIVELY COUPLED PLASMA SOURCE HAVING LOW

DISSOCIATION AND LOW MINIMUM PLASMA VOLTAGE

AMENDMENT UNDER 37 CFR 1.111 TRANSMITTAL

Mail Stop Non-Fee Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

SIR:

Transmitted herewith is an Amendment under 37 CFR 1.111 in response to the Office Action dated October 5, 2005 in the above-identified application. The fee has been calculated as shown below.

	Claims remain- ing after amendment	Highest number previously paid for	Present extra	Rate	Additional Fee
Total Claims	26 minus	26 =	0	x \$50	\$000.00
Independent	2 minus	3 =	0	x \$200	\$000.00
If Multiple Dep	pendent Claims A	re Present, Add \$30	60.00		
	(If applicant is a "small entity," subtract half of total)				\$000.00
		Total addit			\$000.00

[X] No additional fee is required.

[] A check in the amount of \$ is attached.

[X] The Commissioner is hereby authorized to charge any additional fees or deficiencies or credit overpayment to Deposit Account No. 50-0338.

Respectfully submitted,

Dated:

Robert M. Wallace

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Attorney for Applicants

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Robert M. Wallace Patent Attorney 2112 Eastman Avenue, Suite 102 Ventura, CA 93003 (805) 644-4035 CERTIFICATE OF MASSARS

I hereby cartify that this paper and every paper referred to therein to baing exclosed in deposited with the U.S. Peatel Service as first close small, pastage propoid, in an excelope addressed to Commissioner for Peatens, P.O. Ber 160, Advanced by VA 22313-14 on DECT-USER 15, 2005, Quate of Dept.

PATENT

DEC 1 9 2005 W

Attorney Docket No.: 006915 P08

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kenneth COLLINS, et al.

Group Art Unit: 1763

Entitled: PLASMA IMMERSION ION IMPLANTATION SYSTEM INCLUDING A

CAPACITIVELY COUPLED PLASMA SOURCE : HAVING LOW DISSOCIATION AND LOW :

MINIMUM PLASMA VOLTAGE

Examiner: Maureen G.

Serial No.: 10/646,526 : Arancibia

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Filing Date: August 22, 2003

AMENDMENT UNDER 37 CFR 1.111

Mail Stop Non-Fee Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated October 5, 2005, please amend the above-identified patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.